

A fast simulation method for THGEM charging-up study

Based on the G. Song et al 2020 JINST 15 P04015

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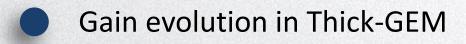
THGEM CHARGING-UP EFFECT

PREVIOUS SIMULATION METHGOD

A FAST SIMULATION METHOD

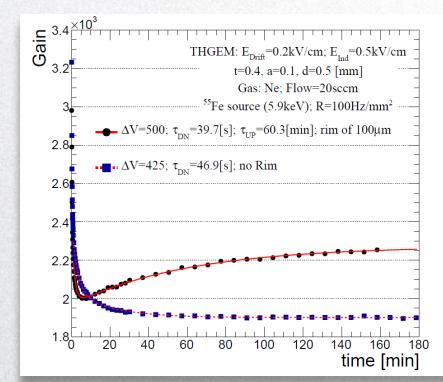
THE RESULTS

CONCLUSIONS AND FUTURE WORK



2 different phenomena:
 Fast gain decrease: few minutes to few tens of minutes

Long gain rise: hours to days, only in THGEM with large rims.

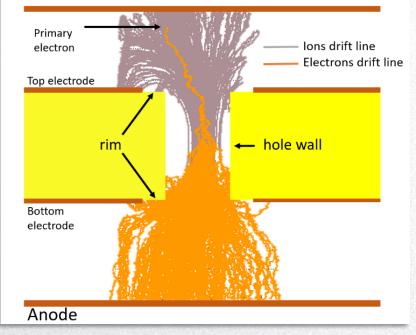


Measured gain stabilization over time M. Pitt *et al* 2018 *JINST* **13** P03009

A qualitative understanding of the gain evolution

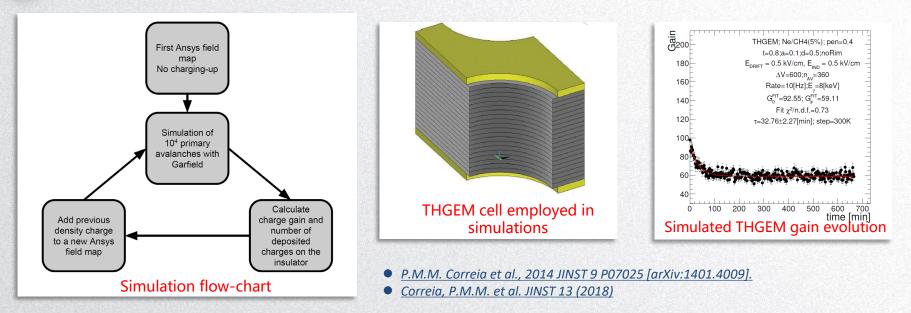
- Charging-up effect: the electrons and ions stop on the dielectric surface of THGEM.
- The field inside a THGEM hole is modified by the net charge accumulation.
 - Gain decreases vs. time: the net charge on hole wall generates an electric field opposite to bias one.
 - Gain increases vs. time: the net charge at the rim surface reinforces the bias electric field.

Cathode



Schematic drawing of the THGEM charging-up

Previous method for Charging-up simulation



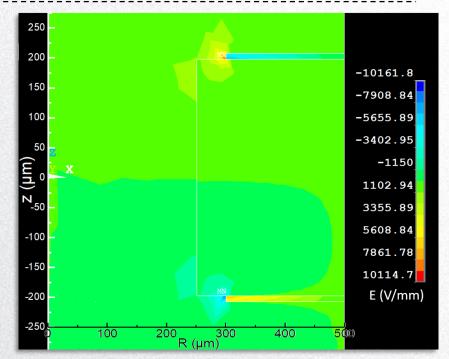
Iterative transition between the FEM software and Garfield++ after each iteration

The step size affects the simulation efficiency and accuracy.

■CPU and time consuming.

2 assumptions for Charge deposition calculation:

- The accumulation of avalanche charges on dielectric surfaces is driven by the electric field component perpendicular to the surface (E_r).
- The condition of equilibrium is that the electric field of the accumulated surface charge fully compensates the initially E_r, so that no more charges accumulate further.



Map of electric field component perpendicular to the THGEM hole wall.

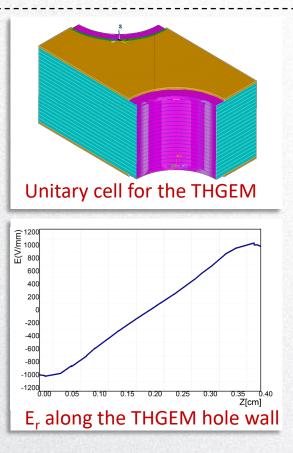


• The electric field generated by the surface charge on the at its own location:

$$E = \frac{\sigma}{\varepsilon + \varepsilon_0}$$

 $\boldsymbol{\varepsilon}$ and $\boldsymbol{\varepsilon}_0$ are the dieletric constant of FR4 and gas.

- Divide the insulator surface into 20 small slices. Use the E_r on each slice of FR4 to calculate charge density σ_i on each slice.
- Add σ_i on each slice, the newly added charge will modify the field map of the THGEM, leading to nonzero E_r again. Thus, we recalculate σ_i until the field map gradually reaches convergence



Superposition calculations for field update

Superposition calculations reduce the use of FEM software.

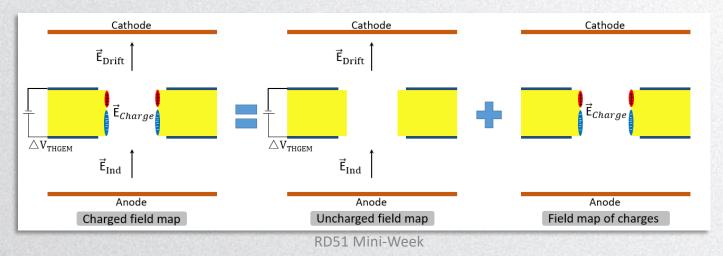
Superposition theorem :

$$\vec{E}_{total} = \vec{E}_{uncharged} + \vec{E}_{charge}.$$
Potential and electric field at each node:

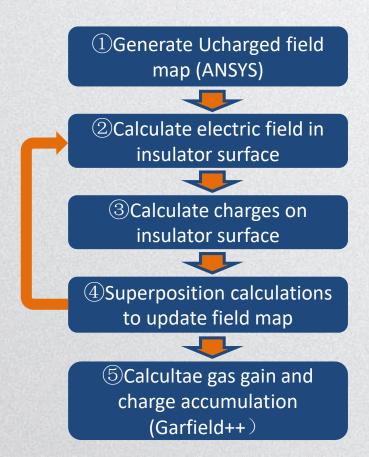
$$\vec{E}_{total}(j) = \vec{E}_{uncharged}(j) + \sum_{i=1}^{20} \sigma_i \vec{E}_{charge}(i, j),$$

$$V_{total}(j) = V_{uncharged}(j) + \sum_{i=1}^{20} \sigma_i V_{charge}(i, j),$$

 $\vec{E}_{charge}(i,j)$ and $V_{charge}(i,j)$ are generated by a unitary positive charge in the surface of slice i



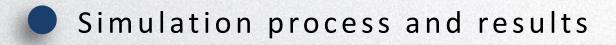
Simulation procedure



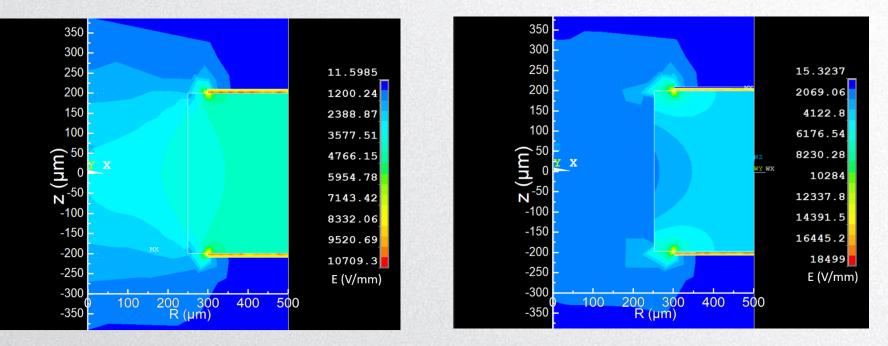
- Superposition theorem is used to update field map,FEM software is only used in the first iteration.
- In each iteration, gas gain and the charge accumulated on the dieletric surface (Q_{ava,i}) are calculated with Garfield++
- The time needed to accumulate charge Q_i for the i-th iteration:

$$\Delta t_i = \frac{Q_i}{Q_{ava,i}} \frac{1}{n_p R}$$

R is irradiation rate, n_p is the number of primary charges.

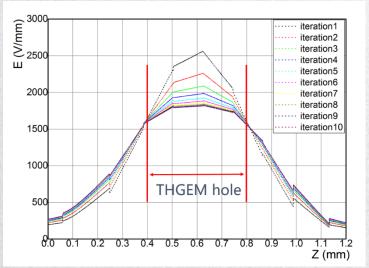


Field map in first iteration(left) and 10th iteration(right)



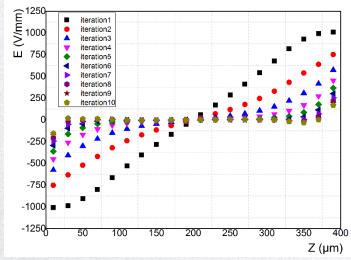
Simulation process and results

THGEM: E_{drift} =0.2kV/cm, E_{ind} =0.5kV/cm, pitch 1mm thickness 0.4mm, diameter 0.5mm,rim 0.1mm, \triangle V=1500V



Total electric field strength along the central axis of the THGEM cylindrical hole at each iteration.

 The electric field in the multiplication region decreased.

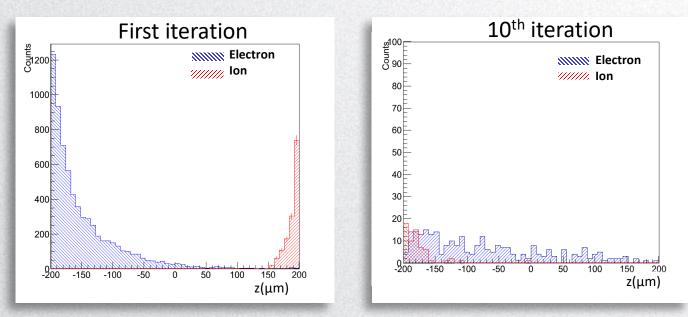


The electric field component perpendicular to the dielectric surface

 We use these field components to estimate the charge accumulation in next iteration

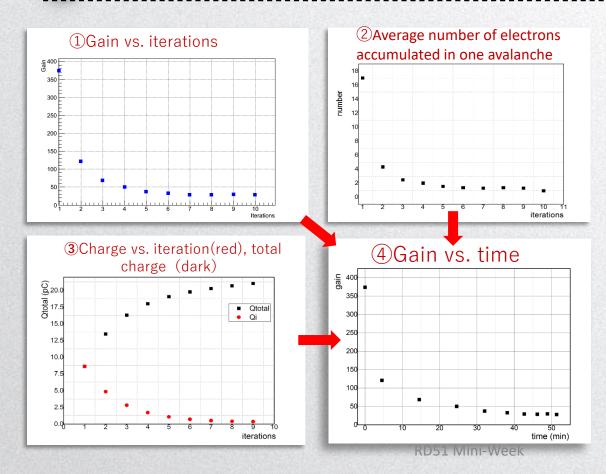
Simulation process and results

Charge accumulation



Charge accumulation along the hole wall in 500 avalanches Calculated with Garfield++

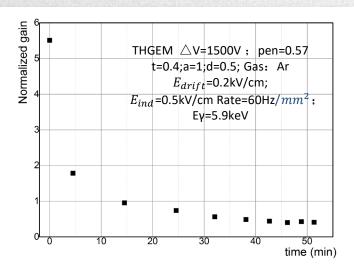
Simulation process and results



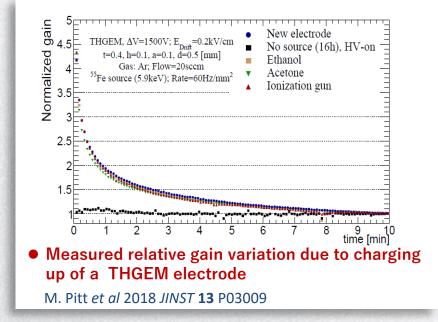
- Gain decreases significantly with increasing iteration
 - Charge accumulation rate decrease with increasing iteration, because the accumulated charge prevents further charge accumulation
 - With charge and it's accumulation speed, the time evolution of the gain can therefore be obtained.

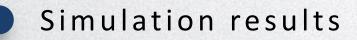


Compare the simulation results with measured data

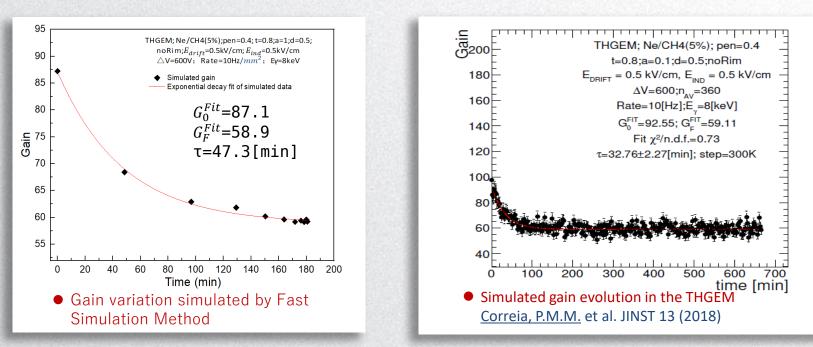


• Gain variation simulated by Fast Simulaiton Method, normalized by iteration3.





Compare the simulation results with previous simulation method



• Fit the simulation result with fuction $G(t)=G_0-\Delta G (1-e^{-t/\tau})$, The fitting results are consistent with precious simulation method.

Conclusions and future work

Conclusions

- We developed a fast iterative method to simulate the charging-up effect of THGEM
- This method only requires a few iterations before reaching gain stabilization.
- The results are in agreement with experimental observations.

Future work

- We neglected the rim effect, we will consider the accumulation of charges on THGEM rims in the future.
- A small amount of avalanche charge still absorbed by the hole wall at last iteration, we may consider the charge migration from the dieletric toward the metallized area.